PROCEEDINGS OF SPIE

9th International Symposium on Advanced Optical Manufacturing and Testing Technologies

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Advanced Optical Manufacturing Technologies

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26–29 June 2018
Chengdu, China

Organized by
Institute of Optics and Electronics, Chinese Academy of Sciences (China)

Sponsored by
COS—The Chinese Optical Society (China)
IOE—Institute of Optics and Electronics, Chinese Academy of Sciences (China)

Published by
SPIE

Volume 10838

Proceedings of SPIE 0277-786X, V. 10838

SPIE is an international society advancing an interdisciplinary approach to the science and application of light.

AOMATT 2018: Advanced Optical Manufacturing Technologies, edited by Xiong Li, William T. Plummer,
Bin Fan, Mingbo Pu, Yongjian Wan, Xiangang Luo, Proc. of SPIE Vol. 10838, 1083801
© 2019 SPIE · CCC code: 0277-786X/19/$18 · doi: 10.1117/12.2523227

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Please use the following format to cite material from these proceedings:
Author(s), "Title of Paper," in *9th International Symposium on Advanced Optical Manufacturing and Testing Technologies: Advanced Optical Manufacturing Technologies*, edited by Xiong Li, William T. Plummer, Bin Fan, Mingbo Pu, Yongjian Wan, Xiangang Luo, Proceedings of SPIE Vol. 10838 (SPIE, Bellingham, WA, 2019) Seven-digit Article CID Number.

ISSN: 0277-786X
ISSN: 1996-756X (electronic)

ISBN: 9781510623187
ISBN: 9781510623194 (electronic)

Published by
SPIE
P.O. Box 10, Bellingham, Washington 98227-0010 USA
Telephone +1 360 676 3290 (Pacific Time) · Fax +1 360 647 1445
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